

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner L. G. Lauchman		Art Unit 2877	Page 1 of 1	

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-6,181,421	01-2001	Aspnes et al.	356/369
	C	US-5,872,630	02-1999	Johs et al.	356/369
	D	US-6,256,097	07-2001	Wagner, Jeff A.	356/369
	E	US-6,515,745	02-2003	Vurens et al.	356/369
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NON-PATENT DOCUMENTS

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	V	"DESIGN OF A SCANNING ELLIPSOMETER BY SYNCHRONOUS ROTATION OF THE□□POLARIZER AND ANALYZER," CHEN ET AL, APPL. OPT. VOL. 33, NO. 7□□(1994).
	W	"ROTATING-COMPENSATOR MULTICHANNEL ELLIPSOMETER FOR□□CHARACTERIZATION OF THE EVOLUTION OF NONUNIFORMITIES IN DIAMOND□□THIN-FILM GROWTH," APPL. PHYS. LETT., VOL. 72, NO. 8 (1998).
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.